

HAMAMATSU

PHOTON IS OUR BUSINESS

Hamamatsu products for OCT applications

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October 2024

Hamamatsu offers diverse products for OCT applications

Hamamatsu offers a variety of components for SD (spectral-domain) OCT, including compact MEMS (micro-electro-mechanical system) mirrors, high-speed linear image sensors, and image sensor circuits/modules. For related applications, we offer balanced detectors, supercontinuum sources, and super luminescent diodes.



MEMS mirrors



Image sensor modules



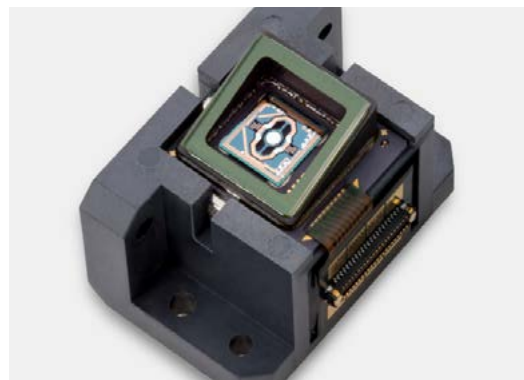
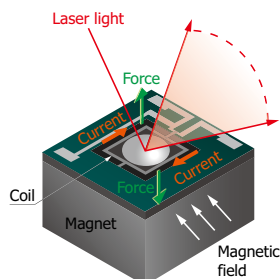
Balanced detectors

MEMS mirrors (electro-magnetic drive)




The MEMS (micro-electro-mechanical system) mirrors offer a wide optical deflection angle, high mirror reflectivity, and low power consumption. Their compact size is attained by arranging the magnet beneath the mirror.

FEATURES

- Compact
- Wide optical deflection angle
- Low voltage drive
- High stability (2D resonant/linear mirror)
- Linear mode type available (1D, 2D)



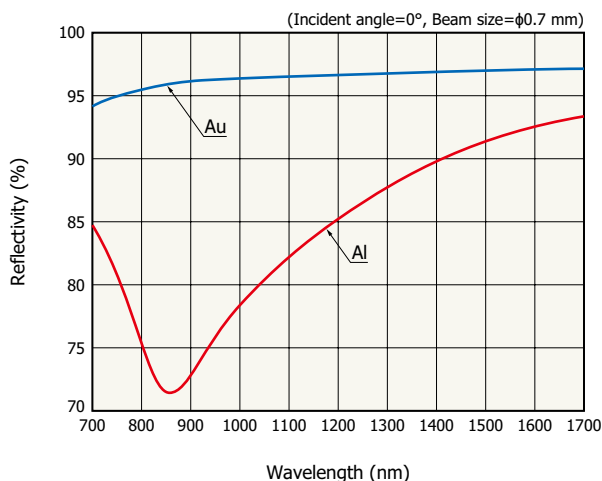
Lineup

Parameter	2D resonant / linear	2D linear	1D linear
	S13989-01H	S13973	S12237-03P
Photo			
Scan mode	Raster (2 axes)	2-axis linear	1-axis linear
Mirror size (mm)	φ1.2	φ2.0	φ2.6
Optical deflection angle	±20° / ±12°	±10° / ±10°	±15°
Operation frequency	29.3 kHz / 100 Hz max.	90 Hz max.	100 Hz max.
Mirror coating	Al* ¹	Au	Al* ¹
Window	Yes* ¹	No	No
Evaluation circuit* ²	C13884HC	C15087	C15087

*1 Please consult a Hamamatsu representative for the availability of Au mirror coating and a window optimized for an NIR region.

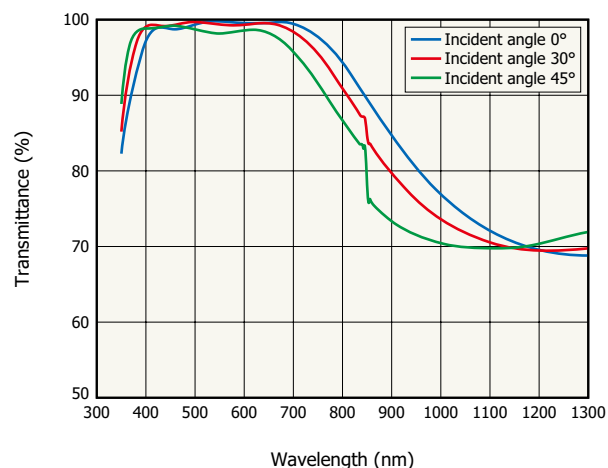
*2 Sold separately

Reflectivity of mirror vs. wavelength



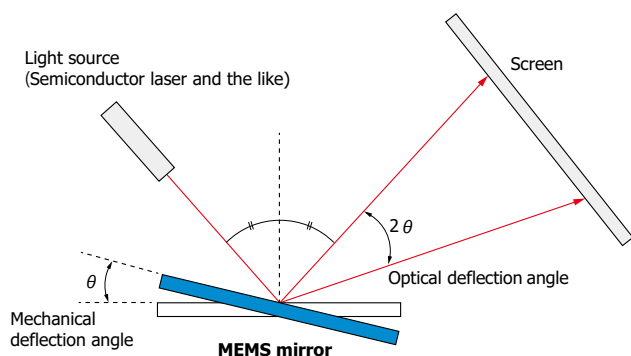
KOTHB0110EB

Spectral transmittance characteristics of window material (typical example)



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■ Relationship between optical and mechanical deflection angles



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► Q&A

Q: Is it possible to enlarge a mirror's size?

A: It is possible. However, there are various factors involved. There are trade-offs in the mirror size, deflection angle, and frequency.

■ Simulated performance examples

Parameter		Mirror size	Optical deflection angle	Frequency
Raster (2 axes)	S13989-01H	φ1.2 mm	±20° / ±12°	29.3 kHz / 100 Hz max.
	Option - 1	φ2.0 mm	±22° / ±14°	10.0 kHz / 60 Hz max.
	Option - 2	φ5.0 mm	±10° / ±10°	to 100 Hz

Option - 1:

- Sine wave, 10kHz high-speed operation is possible.
- Stable operation by suppressing air resistance due to hermetic package
- Low aberration reflective mirror with unique beam structure

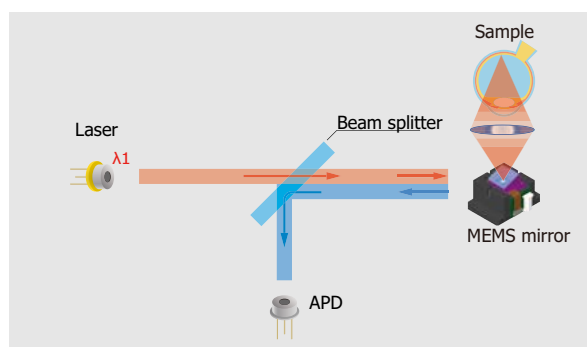
Option - 2:

- Scanning speed corresponding to A-scan rates up to 100 kHz
- Maximum reflection size to take advantage of MEMS mirror features (low cost, low price)
- Deflection angle equivalent to that of galvanometer mirrors

■ Application

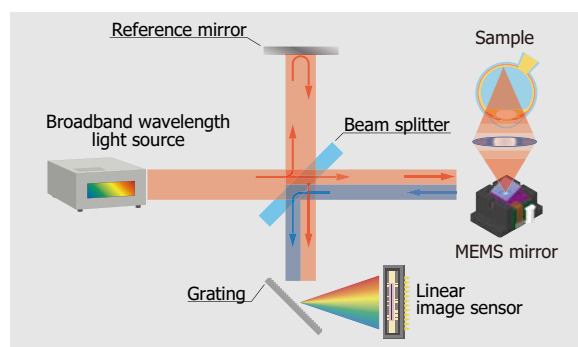
Option - 1: SLO (scanning laser ophthalmoscope)

The object is scanned with a laser beam to acquire an image of the surface.



Option - 2: OCT (optical coherence tomography)

Acquire a tomographic image of the object using the coherence of light.



Please consult a Hamamatsu representative for the development time and cost.

Q: What are the main differences between MEMS mirrors (electro-magnetic) and galvano mirrors?

A: The advantages of the MEMS mirrors are 2 axes capability, compactness, and low cost. These features can allow the creation of new markets.

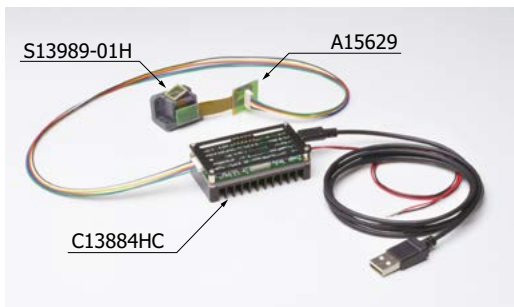
Parameter	MEMS mirror	Galvano mirror
Drive method	Electro-magnetic (Lorentz force)	Motor (Lorentz force)
Optical deflection angle	Good	Very good
Mirror size	Up to a few mm	Large
Device size	Compact	Bulky
Cost	Low	High
2 axes capability	Yes (2 axes mirror available)	No (2 units needed for 2 axes)
Controllability	Requires know-how *Hamamatsu develops dedicated drivers.	Established

Q: Are dedicated driver boards available?

A: Yes, evaluation circuits C15087 (for S12237-03P and S13973) and C13884HC (for S13989-01H) are available. For the low cost mass-production type board, feel free to consult with a Hamamatsu representative. We can customize driver boards after understanding the requirements for your application.

■ Driver software options

- The evaluation circuit can be used as is.
- The evaluation circuit could be modified in the following examples.
 - Serial communication (currently USB communication)
 - Support for development languages (currently C# samples are distributed)
- For S13989-01H (raster scan mirror), an application software can be developed by a user with the driver ASIC (high-speed axis back EMF feedback circuitry) developed by Hamamatsu.
- All driver circuit and software can be designed by a user.

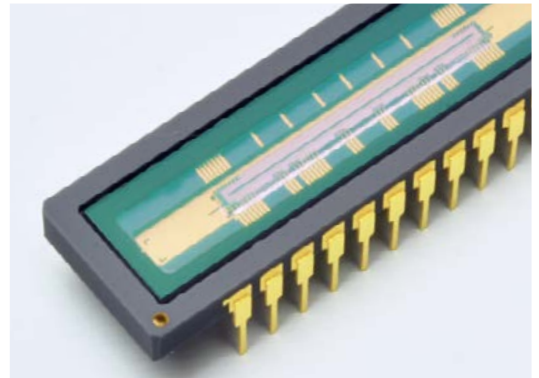


CCD/CMOS linear image sensors for SD-OCT





The CCD/CMOS linear image sensors with enhanced sensitivity in the NIR region are suitable for SD-OCT. The circuit modules are also available.

FEATURES

- NIR sensitivity
High sensitivity from 800 nm to 900 nm is required.
- High line rate
To reduce inspection time, linear image sensors with high line rate are required.
- Rectangular pixels
To achieve fast and accurate inspection, more light needs to be collected, which requires rectangular pixels.

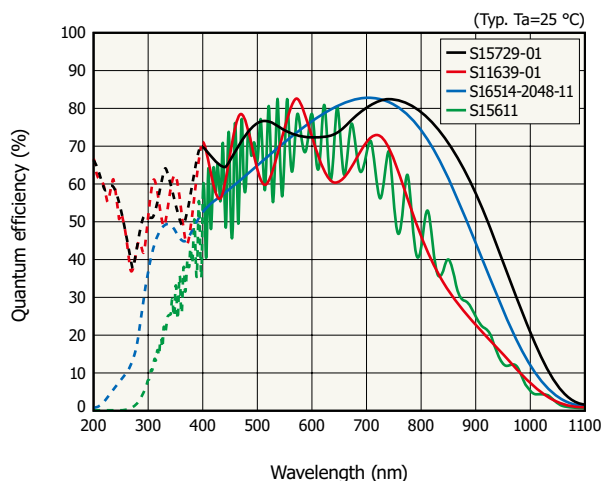


Lineup

Parameter	S15729-01	S11639-01	S16514-2048-11	S15611
Photo				
Type	CCD	CMOS	CMOS	CMOS
Pixel size (μm)	10 × 180	14 × 200	14 × 200	7 × 200
Number of pixels	2048	2048	2048	1024
Line rate (kHz)	70	4.6	4.6	34
Quantum efficiency [at 900 nm]	54%	24%	45%	25%
Output	Analog	Analog	Analog	Digital
Circuit*1	C15821-2351	C16605	C16605	Demo kit

*1 Sensor is sold separately

Spectral response



Demo kit for S15611



* Demo kit for loan only

CCD/CMOS image sensor modules

FEATURES

C15821-2351



- Image sensor module with a built-in CCD linear image sensor
- High line rate: 70 kHz
- Number of pixels: 2048 pixels (512 pixels × 4 taps)
- High NIR sensitivity (>60%, $\lambda=850$ nm)
- Interface: CameraLink

C16605

- Driver circuit developed for Hamamatsu CMOS linear image sensor
- Built-in 16-bit A/D converter
- Compact sensor circuit board that is easy to install in optical systems
- External synchronization capability



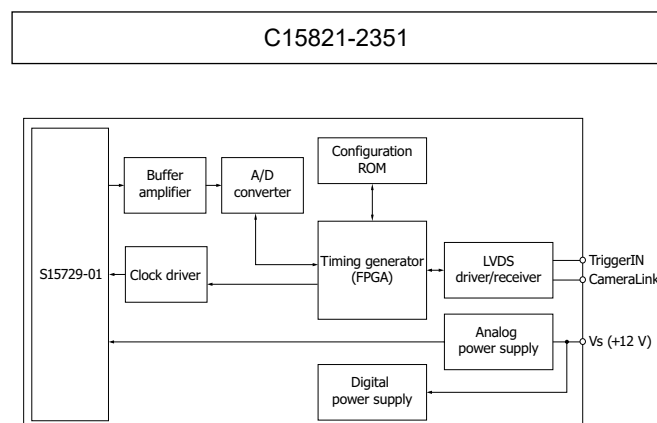
Lineup

Parameter	C15821-2351*1	C16605
Photo		
Image sensor	CCD linear image sensor*2 S15729-01	CMOS linear image sensor S11639-01, etc.*3
Line rate (kHz)	70	4*3
A/D resolution (bit)	10 or 12	16
Dimensions (mm)	60 × 60 × 45.82	Sensor board: 41.6 × 20 × 2.2 Interface board: 50 × 38 × 2.2
Interface	CameraLink	USB 2.0
Supply voltage (V)	+12	+6

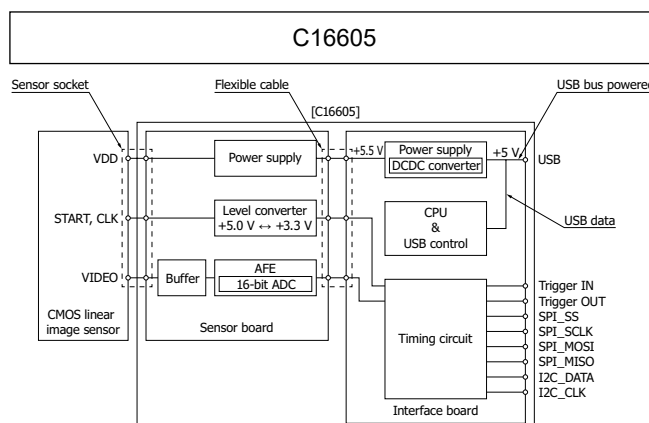
*1 For USB version, consult with your nearest Hamamatsu sales office. *2 Sensor included

*3 Sensor is sold separately. See the C16605 datasheet for applicable sensor and line rate.

Block diagram examples



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Q&A (linear image sensors & modules)

Q: Is it possible to customize an linear image sensor?

A: Yes, it is possible. In addition to the development cost and time frame, we would like to collect the following requirements and priorities.

- a) Number of pixels
- b) Pixel size (pitch, height)
- c) Line rate (What is the minimum requirement? Ideally?)
- d) Target spectral sensitivity and wavelength range
- e) Function (e.g., Do you need an internal A/D converter?)
- f) Cost
- g) Quantity

Q: Is it possible to customize an image sensor module?

A: Yes, it is possible. In addition to the development cost and time, we would like to collect the following requirements and priorities.

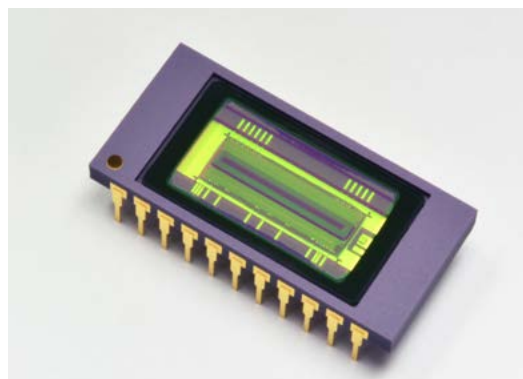
- a) Linear image sensor
 - *The contents of the above Q&A on linear image sensors and the basic performance itself
- b) Size constraints
- c) Interface (CameraLink, Ethernet, USB, etc.)
- d) Housing
- e) A/D converter resolution (number of bits)
- f) Function (external trigger, gain switching, sensitivity compensation, Fourier transform, etc.)
- g) Target price
- h) Quantity

InGaAs linear image sensors for SD-OCT (long wavelength)

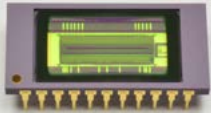
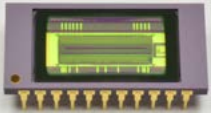
The G14714-1024DG and G14714-1024DK are 1024-channel, high speed line sensors suitable for SD-OCT, with high sensitivity in the near-infrared spectrum. Also Hamamatsu provides camera modules and C15853-03, for plug-and-play solutions.

FEATURES

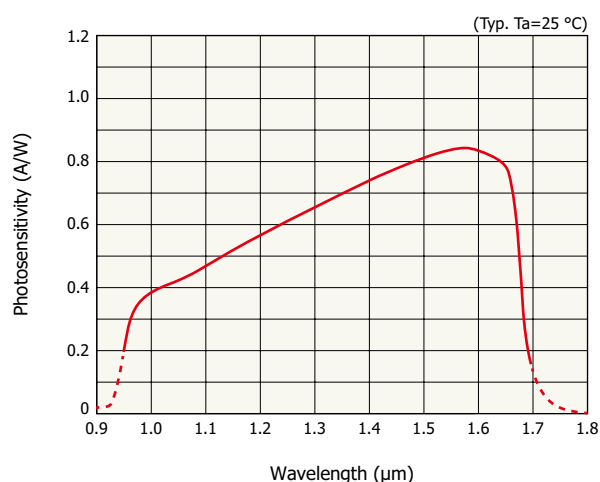
- High line rate (40 kHz max.)
- High sensitivity at 1.0 μm and 1.3 μm
- Room temperature operation (no cooling required)



Lineup

Parameter	G14714-1024DG	G14714-1024DK
Photo		
Pixel size (μm)	12.5 \times 250	12.5 \times 12.5
Number of pixels	1024	1024
Line rate max. (kHz)	40	40

Spectral response



KMIRB0139EA

Image sensor module C15853-03

- For InGaAs linear image sensor G14714-1024DG
- *Sensor included
- Line rate: 40 kHz max.
- USB 3.1 Gen 1



Balanced detectors

The balanced detectors are differential amplification type photoelectric conversion modules that can detect a minute difference by cancelling out common mode noise of two incident light rays.

FEATURES

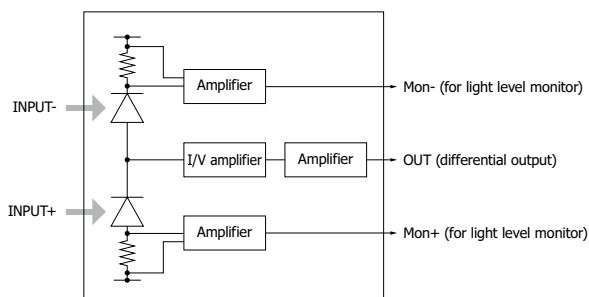
- Employs our unique (patented) structure that reduces multiple reflections at the incident light wavelength of 1.0 μm or 1.3 μm (-01, -02, -03, -04)
- Input section: FC receptacle (APC polished)
A single-mode fiber with an FC connector can be connected.
- Output section: SMA receptacle



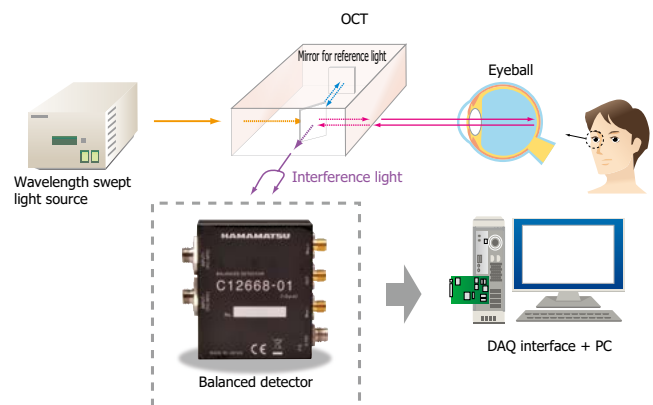
Lineup

Parameter	C12668-01	C12668-02	C12668-03	C12668-04	C12668-05	C12668-06
Photo						
Optimal wavelength band (μm)	1	1.3	1	1.3	1	1.3
Cutoff frequency (MHz)	DC to 200		DC to 400		0.1 to 800	
Common-mode rejection ratio (dB)	35		30		30	
Conversion impedance (kV/A)	15 (50 Ω)		5 (50 Ω)		29 (50 Ω)	
Output noise voltage (mVp-p)	20		20		80	
Supply voltage (V)	± 12		± 12		± 12	
Dimensions (mm)	25 × 54.5 × 65		25 × 78 × 72		18 × 63 × 70	

Block diagram



Connection example (ophthalmic/medical OCT)



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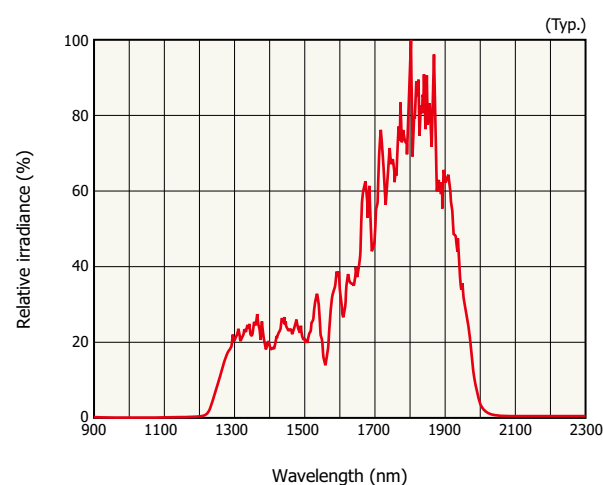
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Supercontinuum light source (New Technology)

The Supercontinuum light source is a highly stable laser light source that outputs a broadband laser beam. It is suitable for measurements of biological samples using the 3rd optical window (1600 to 1800 nm) and enables high resolution deep imaging of highly scattering biological tissues and materials.

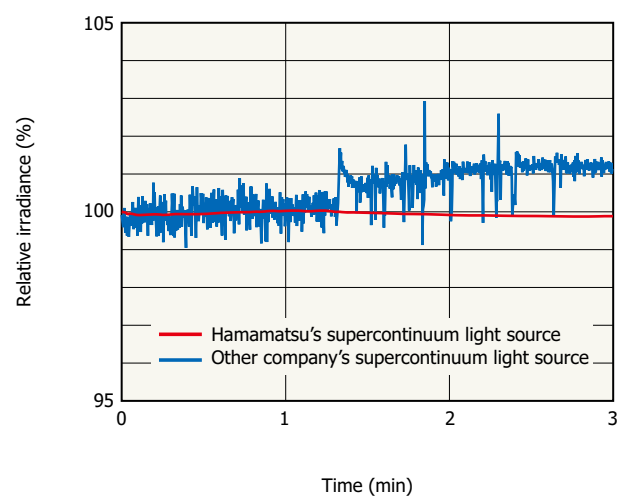
- Characteristics of Supercontinuum light source (example)

■ Spectral distribution



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■ Output stability

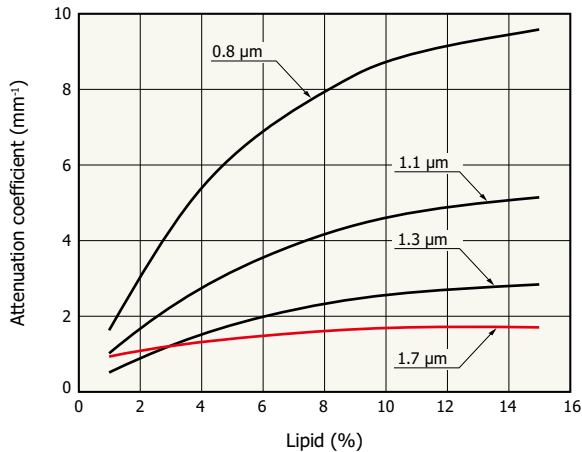


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■ Application: SD-OCT at 3rd optical window

In general OCT, biological tissues containing lipids or hard cells and materials used in industry, such as plastics and magnets, are difficult to observe due to their high light scattering. OCT using broadband light, mainly in the 1700 nm band (3rd optical window), can image deeper regions with higher resolution because the attenuation coefficient for these measurement samples is small, as shown in the figures below.

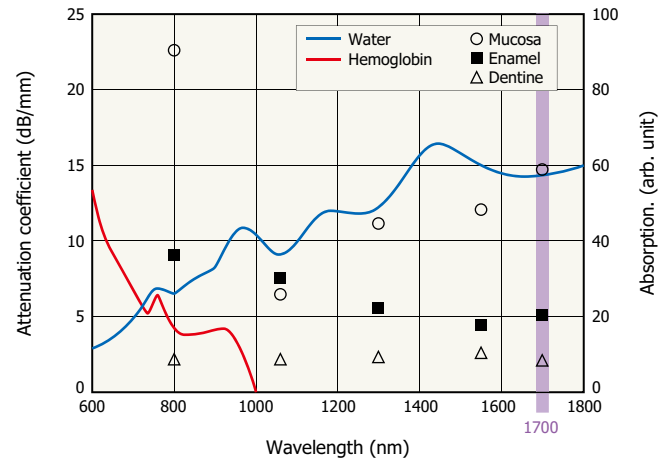
Lipid



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Examples:
Cortex, skin, coronary artery, thyroid gland, trachea, visceral fat

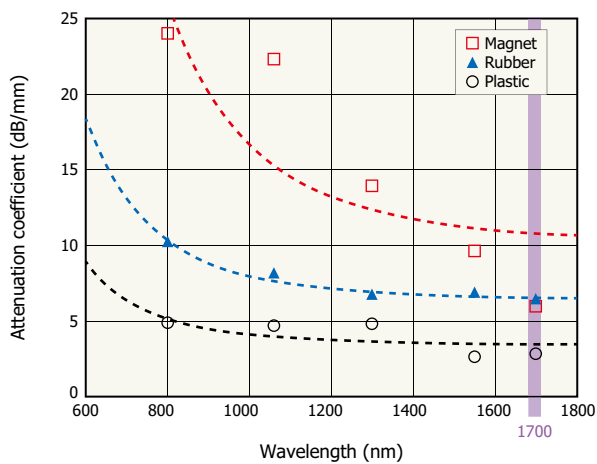
Hard tissue



KOTHB0112EA

Examples:
Periodontal, bone tissue

Industrially used materials



KOTHB0113EA

Examples:
Plastic, rubber, magnet

Reference: S. Ishida, et al., Biomed. Opt. Express 3(2) 282-294 (2012), N. Nishizawa, et al., IEEE J. Sel. Top. Quantum Electron. 25(1), 1 (2019)

Super luminescent diodes (SLD)

- Suitable for eye inspection -

SLDs feature high radiant flux and combine the high brightness of laser diodes with the low coherence of LEDs. They are suitable for optical measurements and medical imaging.

FEATURES

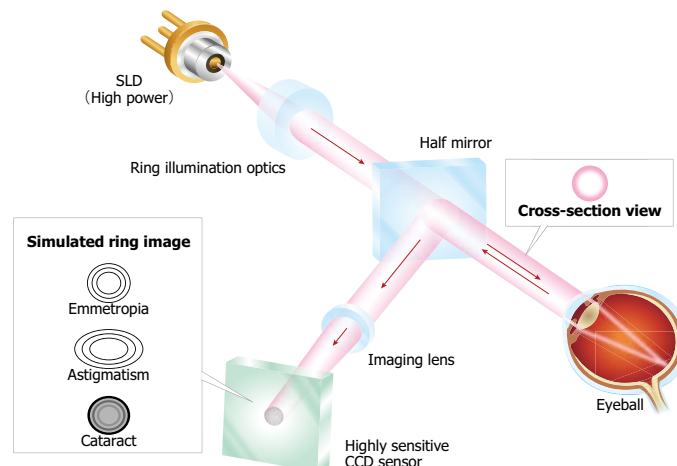
- Non-visible light
- High power: 10 to 30 mW (brighter than LED)
- Narrow spectrum width to avoid interference from other light sources
- No speckle compared to an LD



Lineup

Parameter	L11607-04	L12856-04	Other major SLDs for OCT	
			Example 1	Example 2
Center wavelength (nm)	875 ± 20	830 ± 10	845 ± 25	830 ± 20
Spectrum width FWHM (nm)	10	10	62	15
Radiant flux (mW)	30	10	1 to 2	5
Dimensions (mm)	φ9.0 × 12.1		Fiber or can	

Example of use (Ref-Keratometer)



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Q&A

Q: Are these SLDs suitable for OCT?

A: Yes, one OCT method is best match with our SLDs. These SLDs provide high resolution and high signal-to-noise ratio in ST-OCT due to their high power and narrow spectral width. However, their narrow spectral width and narrow wavelength modulation range make them unsuitable for SD-OCT and SS-OCT. In other applications, these SLDs are also suitable for ocular surface inspection. The high-intensity SLD enables high accuracy measurement in ophthalmometers. The number of cataract patients is increasing due to aging, and high intensity is needed to image the clouding of the eye.

Q: Can SLDs be used to inspect eyeglass lenses?

A: SLD is an ideal light source that does not produce speckle noise and allows precise aberration measurement. For this reason, it is also suitable for inspecting astigmatism and bifocal lenses. In addition, eyeglass lenses have strict transmittance standards, and blue-cut lenses and colored lenses for driving require lens transmittance measurement. A mini-spectrometer C12880MA with sensitivity from UV to near IR is used to measure lens transmittance.

► Related product

■ Mini-spectrometer C12880MA

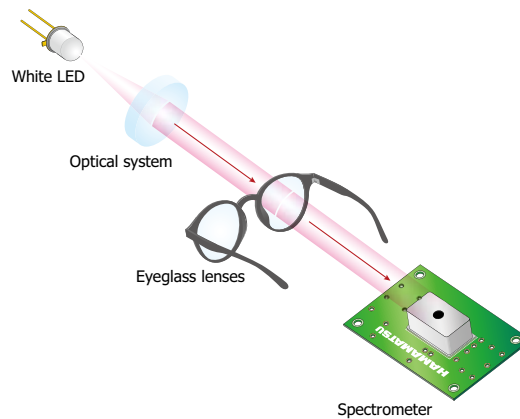
The C12880MA is high-sensitivity, ultra-compact (fingertip-sized) spectrometer head suitable for integration into a variety of compact instruments.

Features

- Fingertip size: $20.1 \times 12.5 \times 10.1$ mm
- Weight: 5 g
- Spectral response range: 340 to 850 nm
- High sensitivity



■ Example of use (Lensmeter)



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OCT overview

What is OCT?

OCT = Optical coherence tomography

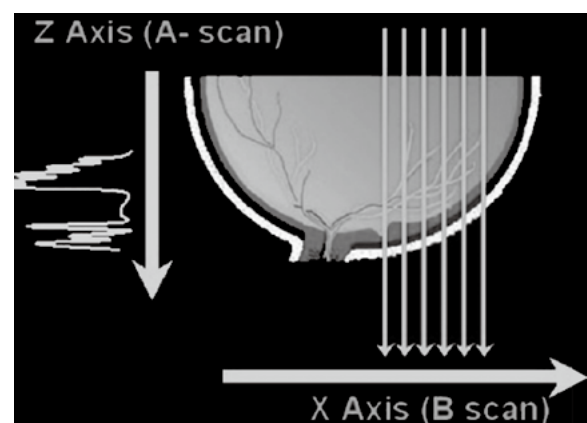
■ Advantages

- High speed: instant imaging, reducing patient burden
- High resolution: μm level resolution, improvement in diagnostic accuracy
- Simultaneity / Promptness: real-time imaging
- Non-invasive: radiation-free, friendly to human body
- Low cost: several million yen to a few ten million yen in instrument price spread among private-practice doctors

Note: Observation area limited to a few μm to a few mm from a surface

Principle

OCT is a technique that can measure distance in the direction of light propagation by utilizing optical interference. When an NIR incident light enters a measurement object, light is scattered backwards and combined with a reference beam in an OCT system to generate optical interference. A 1D signal of the A-scan (depth direction or Z axis) can be obtained with Fourier transform. A tomography image can be obtained by continuously shifting the A-scan along another axis (B-scan).



OCT fundus scan

Types of OCT

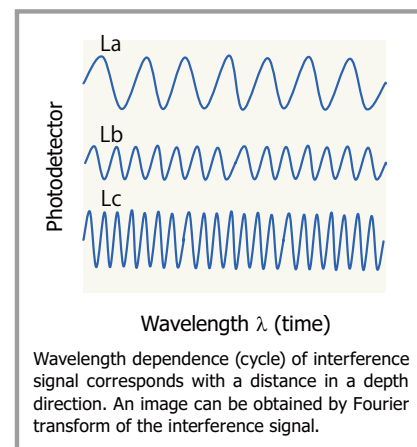
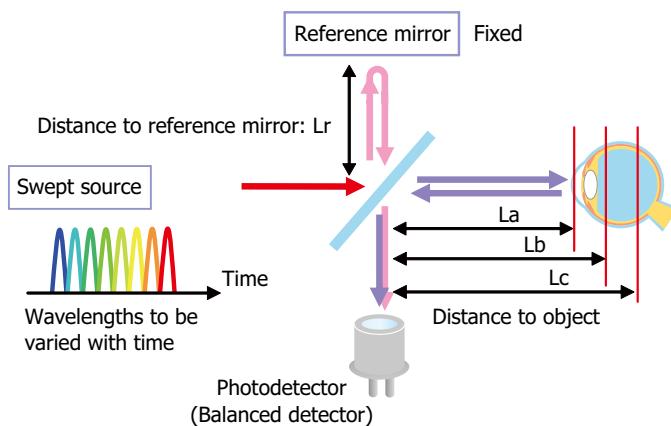
SD (spectral-domain) OCT and SS (swept-source) OCT are both called Fourier-domain OCT as optical signals are converted by Fourier transform. In SD-OCT, backward scattering lights from a measurement object are spatially discriminated with a spectrometer as all the wavelengths from a broadband light source like an SLD (super luminescent diode) are utilized simultaneously. In SS-OCT, signal lights are detected by a point detector (ex. balanced detector) serially as each wavelength enters the object in a sequential order by using a swept light source.

■ SS-OCT structure example

The method below is called SS-OCT.

1. Each wavelength enters a measurement object in a sequential order by sweeping a light source.
2. An optical interference signal between backward scattering and a reference beam is measured with a balanced detector.
3. The interference waveform obtained is converted by Fourier transform to have an image in a depth direction.

A time-resolved spectroscopic analysis of the interference waveforms' wavelength contents is adapted in this method, which is different from SD-OCT.



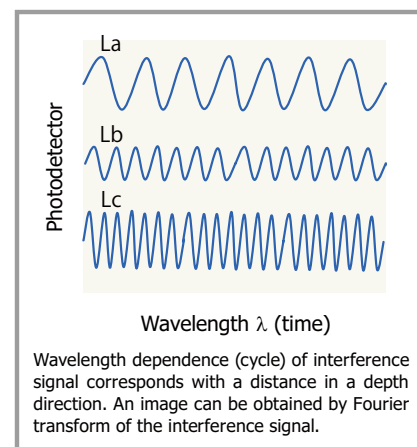
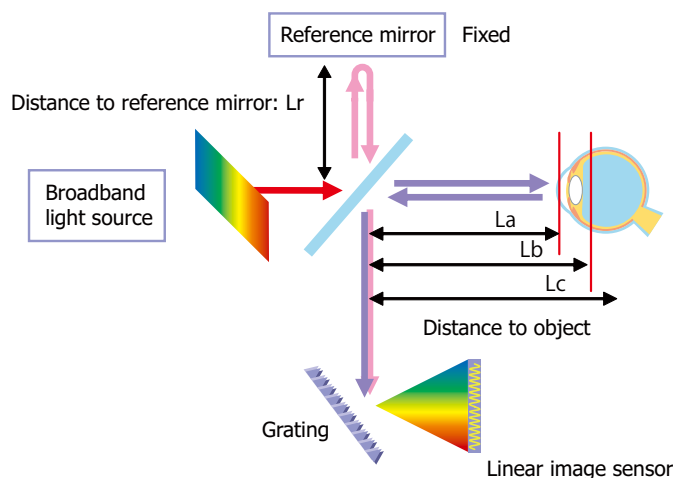
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■ SD-OCT structure example

The method below is called SD-OCT.

1. A broadband light source like an SLD emits light onto a measurement object.
2. Backward scattering lights from the object are spatially discriminated with a spectrometer employing a linear image sensor.
3. The interference waveform obtained is converted by Fourier transform to have an image in a depth direction.

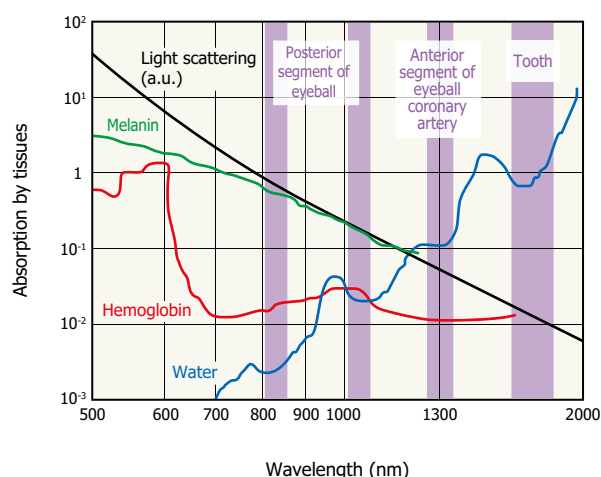
A spectrometer is utilized for measuring the wavelength contents of the interference waveform, which is different from SS-OCT.



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Wavelengths for OCT applications

In biomedical applications, the 800 nm band, 1.0 μm band, and 1.3 μm band are generally utilized because of the smaller influence from water absorption at those wavelengths. Deeper penetration can be achieved using a longer wavelength light due to the decrease of absorption by tissues, but an increase in absorption by water causes less light to reach the tissues (e.g., fundus in ophthalmology), which is a dilemma. For emerging fundus (posterior segment of an eyeball) diagnosis, the use of the 1.0 μm band attracts a great deal of attention because water absorption drops at that long wavelength.



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Information described in this material is current as of October 2024.

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